



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/298,160
Filing Date April 22, 1999
Inventor Dan G. Custer et al.
Assignee Micron Technology, Inc.
Group Art Unit 1746
Examiner A. Olsen
Attorney's Docket No. MI22-1172
Title: Polishing Systems, Methods of Polishing Substrates, and Methods of
Preparing Liquids for Semiconductor Fabrication Processes

PRELIMINARY AMENDMENT TO ACCOMPANY AN RCE FILING
In Response to the December 15, 2000 Final Office Action

To: Box RCE
Assistant Commissioner for Patents
Washington, D.C. 20231

From: Bernard Berman (Tel. 509-624-4276; Fax 509-838-3424)
Wells, St. John, Roberts, Gregory & Matkin P.S.
601 W. First Avenue, Suite 1300
Spokane, WA 99201-3828

Sir:

Responsive to the Final Office Action dated December 15, 2000 and
Applicant submits this Preliminary Amendment with an RCE filing and
respectfully requests reconsideration of the above-references application in
view of the amendments and remarks hereinbelow.

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